

Docket No. F-6971

**RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2882****IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Seiichi HAYASHI, et al.
Serial No. : 09/852,111
Filed : May 9, 2001
For : METHOD AND APPARATUS FOR MEASURING THIN
FILM, AND THIN FILM DEPOSITION SYSTEM
Group Art Unit : 2882
Examiner : Hoon K. Song
Confirmation No. : 5010
Customer No. : 000028107

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AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR 1.116

Docket No. F-6971

Scr. No. 09/852,111

INTRODUCTORY COMMENTS:

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Sir:

In response to the final Office Action of June 30, 2004, entry of the present amendment to place the application into condition for allowance or remove issues from appeal, if required, is respectfully requested. Please amend the above-identified patent application as follows: